Single Wafer Spin Processors

With options ranging from pressure vessels for chemical dispense, to chemical re-circulation heating, the systems offer you complete process solutions.

Your Local Distributor:

- Static barrier plate
- Vertical lid opener
- Syringe Holder for controlled manual dispense

Units for up to 1 meter substrates

Complete solutions
Single Wafer Spin Processors

The versatile, high-quality, all plastic spin<sup>®</sup> and spin<sup>150</sup> Single Substrate Spin Processors are specially designed for MEMS, R&D, typically low-volume applications: cleaning, rinse/dry, coating, developing and etching.

<table>
<thead>
<tr>
<th>CHEMICAL DISPENSE</th>
<th>MODEL</th>
<th>SUBSTRATE SIZE</th>
</tr>
</thead>
<tbody>
<tr>
<td>Manual Dispense</td>
<td>SPIN150</td>
<td>Up to Ø 160mm (4’’ x 4’’)</td>
</tr>
<tr>
<td></td>
<td>MCD200-NPP</td>
<td>Up to Ø 260mm (6’’ x 6’’)</td>
</tr>
<tr>
<td>Automatic Dispense</td>
<td>ACD200-NPP</td>
<td>Up to Ø 260mm (6’’ x 6’’)</td>
</tr>
<tr>
<td></td>
<td>ACD200-PTFE</td>
<td>Up to Ø 360mm (10’’ x 10’’)</td>
</tr>
<tr>
<td>Manual Dispense</td>
<td>MCD300-NPP</td>
<td>Up to Ø 360mm (10’’ x 10’’)</td>
</tr>
<tr>
<td></td>
<td>MCD300-PTFE</td>
<td>Up to Ø 360mm (10’’ x 10’’)</td>
</tr>
<tr>
<td>Automatic Dispense</td>
<td>ACD300-NPP</td>
<td>Up to Ø 360mm (10’’ x 10’’)</td>
</tr>
<tr>
<td></td>
<td>ACD300-PTFE</td>
<td>Up to Ø 360mm (10’’ x 10’’)</td>
</tr>
</tbody>
</table>

The polypropylene spin<sup>150</sup> with its high speed precision motor, standard vacuum chuck, fragment adapter and syringe holder, 100 freely programmable programs, and capability for up to Ø160mm substrates, is a high-value, low-budget tabletop unit.

The more versatile spin<sup>®</sup> series can be supplied as a stand-alone table-top unit or recessed in-bench (OEM) version: ranging from manual (MCD) to fully automatic chemical dispense (ACD), in NPP or Teflon<sup>®</sup>/PTFE.

Various models are available for processing a wide range of substrates ranging from small fragments up to Ø300mm (and larger substrates on request), as standard with vacuum or mechanical chuck. Custom chucks are available for almost any application, making this the ideal tool for process research and development. Systems are constructed in Natural Polypropylene, or high grade Teflon<sup>®</sup>/PTFE (TFM1600<sup>®</sup>). The clear, transparent, hinged lid allows easy access to load/unload substrates to the chuck.

The gloved-finger friendly panel with backlit display allows easy programming of: time, acceleration (adjustable in 1 rpm/sec.) and spin speed: ranging from 1 to 10.000rpm (spin speed accuracy 0.1rpm). Sub D9 pins connector offers 2 extra programmable output signals.
Single Wafer Spin Processors

Spin Processors are available as OEM in-bench versions, featuring separate control panel for implementations at the front-side of the wet bench. (Table Top models have integrated keyboard.)

Standard MCD200 and ACD200 units are suitable for processing from fragments, up to Ø200mm or 6"x6" square substrates. Models are available for processing Ø300mm wafers and for larger substrates (up to 1000mm) on request. MCD models feature a centre hole in the flat glass lid for manual fluid dispense. ACD models are supplied as standard with 2 spray nozzles (max. up to 6), corresponding suckback valves, and a central nitrogen diffuser in an ECTFE, dome-shaped lid. All units and chucks are made out of Natural Polypropylene, or Teflon®/PTFE.

<table>
<thead>
<tr>
<th>Fragments</th>
<th>Round Substrates</th>
<th>Round Substrates</th>
<th>Round Substrates</th>
<th>Round Substrates</th>
</tr>
</thead>
<tbody>
<tr>
<td>Dies, Wafer, Fragments, etc.</td>
<td>Vacuum for 2&quot; up to 300mm Wafers</td>
<td>(Vacuum and Centering pins)</td>
<td>(Mechanical and Centering pins)</td>
<td>(Vacuum and Centering pins)</td>
</tr>
<tr>
<td>Low Contact</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Square Substrates</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Masks, Solar Cells, etc.</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Regular Substrates</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Laboratory Glass, etc.</td>
<td></td>
<td></td>
<td></td>
<td></td>
</tr>
<tr>
<td>Thin, Fragile Substrates</td>
<td>Foil, etc.</td>
<td></td>
<td></td>
<td></td>
</tr>
</tbody>
</table>

Customized vacuum or mechanical chucks are available for almost any application.

www.SPS-Europe.com
Single Wafer Spin Processors

With options ranging from pressure vessels for chemical dispense, to chemical re-circulation heating, the systems offer you complete process solutions.

Static barrier plate

Vertical lid opener

Syringe Holder for controlled manual dispense

Units for upto 1 meter substrates

SPS-Europe B.V.
Midden Engweg 41
3882 TS Putten
The Netherlands
Tel.: (31) 341 360 590
Fax: (31) 341 360 589
info@sps-europe.com

S.P.S. Ltd.
Tweed Horizons Centre
Newtown St. Boswells
TD6 6SG Scotland
Tel.: (44) 1835 822 455
Fax: (44) 1835 822 055
info.uk@sps-europe.com

S.P.S. Vertriebs GmbH
Rosenstrasse 10
D-85053 Ingolstadt
Germany
Tel.: (49) 841 370 530
Fax: (49) 841 370 5322
info.de@sps-europe.com

S.P.S. bvba
9, Rue du Pont à Lunettes
F-69390 Vourles
France
Tel.: (33) 472 31 78 35
Fax: (33) 478 05 13 45
info.fr@sps-europe.com

S.P.S. bvba
Via G. Verdi 18b
27021 Bereguardo (PV)
Italy
Tel.: (39) 0362 920 739
Fax: (39) 0362 920 738
info.it@sps-europe.com

Your Local Distributor: